



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of: Hashim et al. §
Serial No.: 09/138,429 §
Filed: August 24, 1998 §
For: Collimated and Long Throw §
Magnetron Sputtering of Nickel/Iron §
Films for Magnetic Recording §
Head Applications §
Group Art Unit: 1753
Examiner: Mercado, J.

Assistant Commissioner for Patents
Washington, D.C. 20231

Dear Sir:

CERTIFICATE OF MAILING 37 C.F.R. 1.8	
I hereby certify that this correspondence is being deposited on 1/17, 2001, with the U. S. Postal Service as First Class Mail in an envelope addressed to: Assistant Commissioner for Patents, Washington, D.C. 20231.	
1/17/01 Date	B. J. Patterson Signature

RESPONSE TO OFFICE ACTION DATED OCTOBER 17, 2000

In response to the Office Action dated October 17, 2000, having a shortened statutory period for response set to expire on January 17, 2001, Applicants request entry and consideration of the following amendments as discussed herein. The Commissioner is hereby authorized to charge Deposit Acct. No. 20-0782/AMAT/2406.X1/CPES/ST/NAN for any fees necessary to render this response timely.

IN THE CLAIMS:

Please amend the following claims:

- C1
1. (Amended) An apparatus for depositing a magnetic film, comprising:
a sputtering chamber containing a target, a substrate support having a surface that is separated from the target, and a grounded collimator positioned between the target and the substrate support; and
an annular magnet array disposed within the chamber to form a [stationary] magnetic